

TRANSMITTAL

Electronic Version v1.1

Stylesheet Version v1.1.0

Title of Invention	Method of Forming Thin Silicon Oxide Films on Silicon Carbide Substrates	
Application Number :		
Date :		
First Named Applicant:	Andrew M. Hoff	
Confirmation Number:		
Attorney Docket Number:	1372.80.PRC	
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Submitted By:		Elec. Sign.
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Documents being submitted:	Files
us-request	1372_80_PRC-usrequ.xml us-request.dtd us-request.xsl
us-declaration	1372_80_PRC-usdecl.xml us-declaration.dtd us-declaration.xsl
us-fee-sheet	1372_80_PRC-usfees.xml us-fee-sheet.xsl us-fee-sheet.dtd
us-power-of-attorney-grant	1372_80_PRC-uspoat.xml us-power-of-attorney-grant.dtd us-power-of-attorney-grant.xsl
application-body	Specification-trans.xml us-application-body.xsl application-body.dtd
	wipo.ent mathml2.dtd mathml2-qname-1.mod isoamsa.ent isoamsb.ent isoamsc.ent isoamsn.ent isoamso.ent isoamsr.ent isogr3.ent isomfrk.ent isomopf.ent isomscr.ent isotech.ent isobox.ent isocyr1.ent isocyr2.ent isodia.ent isolat1.ent isolat2.ent isonum.ent isopub.ent mmlextra.ent mmlalias.ent soextblx.dtd FIG0102_1.TIF
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